

### **Amendments to the Specification**

Please replace the paragraph beginning on page 3, line 29, with the following:

-- FIG. ~~1A~~ illustrates a high-level block diagram of a laser thermal (LT) printer system; --

Please replace the paragraph beginning on page 4, line 1, with the following:

-- FIGS. ~~1A and 1B~~ 1B and 1C illustrate a side view and top view, respectively, of the laser thermal (LT) printer system of FIG. 1 for use in an OLED fabrication process; --

Please replace the paragraph beginning on page 5, line 9, with the following:

-- FIG. ~~1A~~ illustrates a high-level block diagram of laser thermal (LT) printer system **100** for use in an OLED fabrication process. LT printer system **100** includes a vacuum chamber **122**, a controller **111**, a motion control system **110** upon which is mounted a laser thermal (LT) station **112**, and a detection system **114**. Laser light beams can be directed to either the vacuum chamber **122** or the detection system **114** depending upon the positional commands **113** sent to the motion control system **110**, and further depending upon the printhead control commands **115** sent by the controller **111** to the LT station **112**. In response to the receipt of laser light beams directed to the correct portion of detection system **114**, and upon commands from the controller **111**, the detection system **114** will return irradiance data **117** to the controller **111**. During the gathering of irradiance data **117**, the controller **111** also gathers positional data **119** from the motion control system **110**. --

Please replace the paragraph beginning on page 5, line 22, with the following:

-- FIGS. ~~1A and 1B~~ 1B and 1C illustrate a more detailed side view and top view, respectively, of portions of laser thermal (LT) printer system **100** including the motion control system **110** upon which is mounted an LT station **112** and a detection system **114**. --

Please replace the paragraph beginning on page 6, line 31, with the following:

-- A narrow aperture of uniform gap, sometimes referred to as a slit aperture, is shown as X-slit aperture **130** in FIG. ~~1B~~ 1C, and another is shown

as Y-slit aperture **134**. These are custom aperture devices that have narrow openings (i.e., slit **132** and slit **136**, respectively) through which light passes. Slit **132** and slit **136** are oriented orthogonal to one another, as shown in FIG. ~~4B~~ 1C. X-photodetector **138** and Y-photodetector **140** are conventional optical sensors, such as United Detector Technology PIN 6DI, for detecting the laser light wavelength band. --